## Kinetic Control of Catalytic CVD for High Quality Graphene at Low Temperatures

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## Abstract

Chemical vapour deposition (CVD) is the most promising route towards scalable graphene production and integration, key requirements for the commercial exploitation of graphene's unique properties. The growth of high-quality, uniform monolayer graphene (MLG) has been well demonstrated on polycrystalline Cu foils, however this generally requires excessive temperature (~1000°C), and low pressures which result in significant catalyst sublimation.

Ni based catalysts have been shown to be effective for graphene growth at much lower temperatures (450-600°C).<sup>1</sup> We use in situ, time-, and depth-resolved X-ray photoelectron spectroscopy (XPS) and insitu X-ray diffraction (XRD) to monitor graphene formation under realistic CVD conditions.<sup>1,2</sup> In particular, we reveal that graphene growth occurs during isothermal hydrocarbon exposure, rather than being limited to a precipitation process upon cooling, and that carbon dissolved in to the catalyst subsurface plays a critical role.

Here, we use this understanding to realise scalable graphene CVD on Ni-based catalysts at ~600°C with complete MLG coverage, achieving uniformity and quality that has hitherto only been reported for Cu-based CVD at >900°C.<sup>3</sup> Raman mapping reveals a 2D/G ratio of >3.2, D/G ratio  $\leq$  0.08 and transport measurements show carrier mobilities of  $\geq$ 3000 cm<sup>2</sup>V<sup>-1</sup>s<sup>-1</sup> on SiO<sub>2</sub> supports.

We establish a kinetic growth model for graphene CVD based the balance of carbon fluxes at the catalyst surface,<sup>4</sup> which is well supported by our systematic study of Ni-based polycrystalline catalysts. A finite carbon solubility of the catalyst is shown to be a key advantage, as it allows the catalyst bulk to act as a mediating carbon sink while optimized graphene growth occurs by only locally saturating the catalyst surface with carbon. This enables a route to the controlled formation of Bernal stacked bi- and few-layered graphene. The model developed is relevant to all catalyst materials and can readily serve as a general process rationale for optimised graphene CVD.

## References

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